

## AMENDMENTS TO THE SPECIFICATION

Please amend paragraph [0001] as follows.

[0001] This patent document is related to and hereby incorporates by reference in their entirety the following co-filed U.S. patent applications: Ser. No. ~~UNKNOWN~~ 10/666,319, entitled "Alignment Post for Optical Subassemblies Made With Cylindrical Rods, Tubes, Spheres, or Similar Features", ~~Attorney Docket No. 10030442-1~~; Ser. No. ~~UNKNOWN~~ 10/666,363, entitled "Wafer Level Packaging of Optoelectronic Devices", ~~Attorney Docket No. 10030489-1~~; Ser. No. ~~UNKNOWN~~ 10/666,442, entitled "Integrated Optics and Electronics", ~~Attorney Docket No. 10030566-1~~; Ser. No. ~~UNKNOWN~~ 10/666,444, entitled "Methods to Make Diffractive Optical Elements", ~~Attorney Docket No. 10030769-1~~; Ser. No. ~~UNKNOWN~~ 10/666,091, entitled "Optoelectronic Device Packaging With Hermetically Sealed Cavity and Integrated Optical Element", ~~Attorney Docket No. 10030386-1~~; Ser. No. ~~UNKNOWN~~ 10/665,680, entitled "Optical Device Package With Turning Mirror and Alignment Post", ~~Attorney Docket No. 10030768-1~~; and Ser. No. ~~UNKNOWN~~ 10/665,660, entitled "Optical Receiver Package", ~~Attorney Docket No. 10030808-1~~.

Please amend paragraph [0031] as follows.

[0031] Sub-mount 300 can be fabricated using wafer processing techniques such as those described in a co-filed U.S. Pat. App. No. ~~UNKNOWN~~ 10/666,442, entitled "Integrated Optics And Electronics", ~~Attorney Docket No. 10030566-1~~. In the illustrated embodiment, sub-mount 300 can either be a processed or unprocessed silicon substrate and could incorporate passive and/or active circuit components.

Please amend paragraph [0038] as follows.

[0038] A thin polysilicon layer 516 (e.g., about 1  $\mu\text{m}$  or less) is then deposited on etch stop layer 514. Polysilicon layer 516 acts as a base for formation of an optical element 530 but is thin enough to be transparent to the wavelength of light emitted from the laser being packaged. In an example, lens 530 is formed on layer 516, for example, by building up alternating layers of polysilicon and oxide to achieve the desired shape or characteristics of a diffractive or refractive lens. A co-filed U.S. Pat. App. No. ~~UNKNOWN~~ 10/666,444, entitled "Methods to Make Diffractive Optical Elements",

~~Attorney Docket No. 10030769-1~~, describes some suitable processes for fabrication of lens 530.

Please amend paragraph [0046] as follows.

[0046] A post 660 is attached (e.g., epoxied or glued) to cap 630 at the location where the light exits cap 630. Post 660 acts as an alignment feature that aligns the light emitted from the optoelectronic device 610 to an optical fiber. In one embodiment of the invention, post 660 is a hollow cylinder having an inner diameter larger than the beam profile. Post 660 can thus be made of any suitably durable material such as metal. Alternatively, post 660 can be a solid structure such as a cylinder or a sphere of an optically transparent material. Alignment posts for packages containing optical devices are further described in a co-filed U.S. Pat. App. Ser. No. ~~UNKNOWN~~ 10/666,319, entitled "Alignment Post for Optical Subassemblies Made With Cylindrical Rods, Tubes, Spheres, or Similar Features", ~~Attorney Docket No. 10030442-1~~.